

Wafer Inspection System (WIS)

The Wafer Inspection system **WIS** is high-quality equipment for examining wafers. The selection of one or several wafer which can be examined is purposefully possible over an automatic program or manually over control panel. The wafer is lifted out upward over a wafer grab segment and a stroke unit from the carrier and can be turned alternatively into different directions.

The handling and configuration of the equipment as well as the mechanism of the program sequences can be made user-friendly over an external operating panel. Only high-quality materials are used with the production of the **WIS**. They are the basis for a long life span and ensure the working reliability with each processing step. Therefore the **WIS** is suitable ideally for the use in the cleanroom.

Please indicate the carrier identification as well as the wafer size for your order.

The equipment is available for wafer sizes of 4" to 8".



Electrical connection data

Supply voltage	110 – 240 V
Capacity maximally	120 VA
Frequency	50/60 Hz
Safety class system	I
Connecting cable	3 x 1mm ² >= 2,5m long
Connection	Cold device plug 3-pin

Order remarks

29784	Wafer Inspection System (servo) in different sizes of 4" - 8"
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Accessories

19536	WIS Operating panel (included in delivery)
31142	WIS Stroke unit (included in delivery)
Diverse Ausführungen	WIS Wafer grab segment (included in delivery)

Generally

Width	400 mm
Height	418 mm
Depth	240 mm
Weight	25 kg (incl. operating sector)